

Oct 15, 1998
S/N 08/902,809

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Klaus Florian Schuegraf et al.

Examiner: Ori Nadav

Serial No.: 08/902,809

Group Art Unit: 2811

Filed: July 30, 1997

Docket: 303.278US1

Title: SELECTIVE SPACER TECHNOLOGY TO PREVENT METAL OXIDE
FORMATION DURING POLYCID REOXIDATION

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AMENDMENT AND RESPONSE

10-23-98

Assistant Commissioner for Patents
Washington, D.C. 20231

In response to the Office Action mailed June 9, 1998, to which a one month extension of time has been obtained, please amend the above-identified application as follows:

IN THE TITLE

Please replace the title with the following new title: --Selective Spacer To Prevent Metal Oxide Formation During Polycide Reoxidation--.

IN THE SPECIFICATION

On page 4, line 22, change "nitride" to --polysilicon, a refractory metal, and a dielectric--.

On page 4, line 26, change "refractory metal 205" to --refractory metal of electrode 205--.

On page 5, line 3, change "polycide reoxidation" to -- polycide reoxidation 220--.

On page 5, line 6, change "reoxidized" to --reoxidized 220--.

On page 5, line 9, change "metal layers 205" to --metal layers--.

On page 5, line 13, change "undoped silicon" to --undoped silicon 211 with reoxidation 221--.

IN THE ABSTRACT

Please replace the abstract with a new abstract attached hereto as a separate page.

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